



*EFW*

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 2322**  
Yoichiro YASHIRO et al. : Attorney Docket No. 2003\_1205A  
Serial No. 10/647,479 : Group Art Unit 1762  
Filed August 26, 2003 : Examiner Cachet I. Sellman

PLASMA PROCESSING METHOD  
AND APPARATUS

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**RESPONSE**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Restriction Requirement of June 6, 2006, Applicants hereby elect Group II, which is drawn to an apparatus and is embodied by claims 12-17.

Having made the required election, a full examination on the merits of the elected group is requested.

Respectfully submitted,

Yoichiro YASHIRO et al.

By: *Michael S. Huppert*

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THE COMMISSIONER IS AUTHORIZED  
TO CHARGE ANY DEFICIENCY IN THE  
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ACCOUNT NO. 23-0975

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June 28, 2006